

Figure 1A (PRIOR ART)

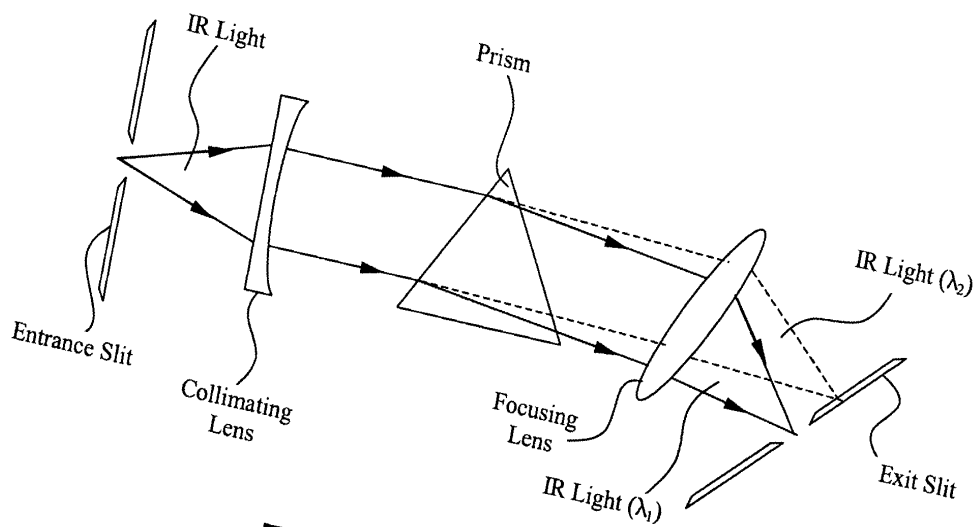


Figure 1B (PRIOR ART)

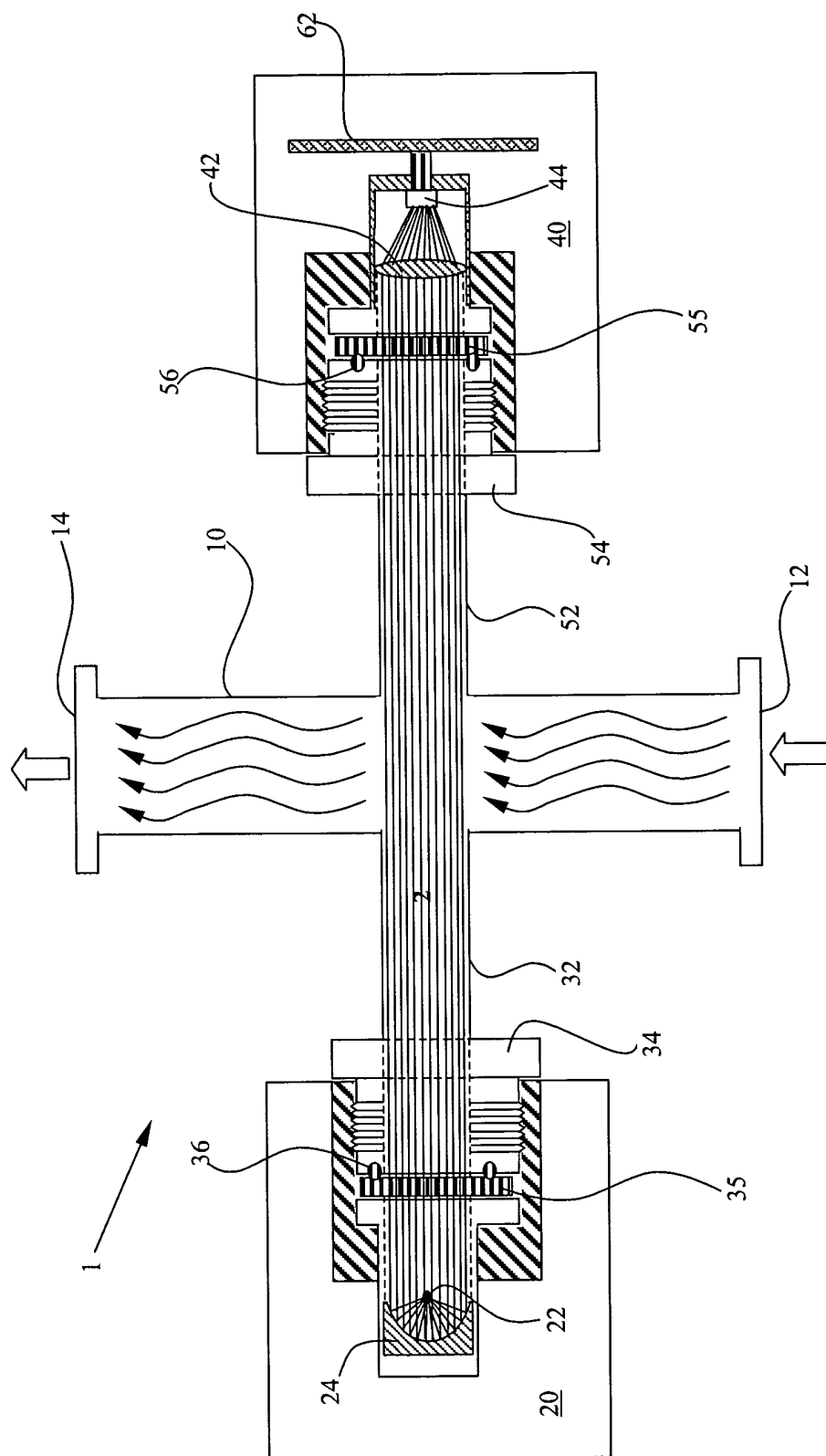


Figure 2

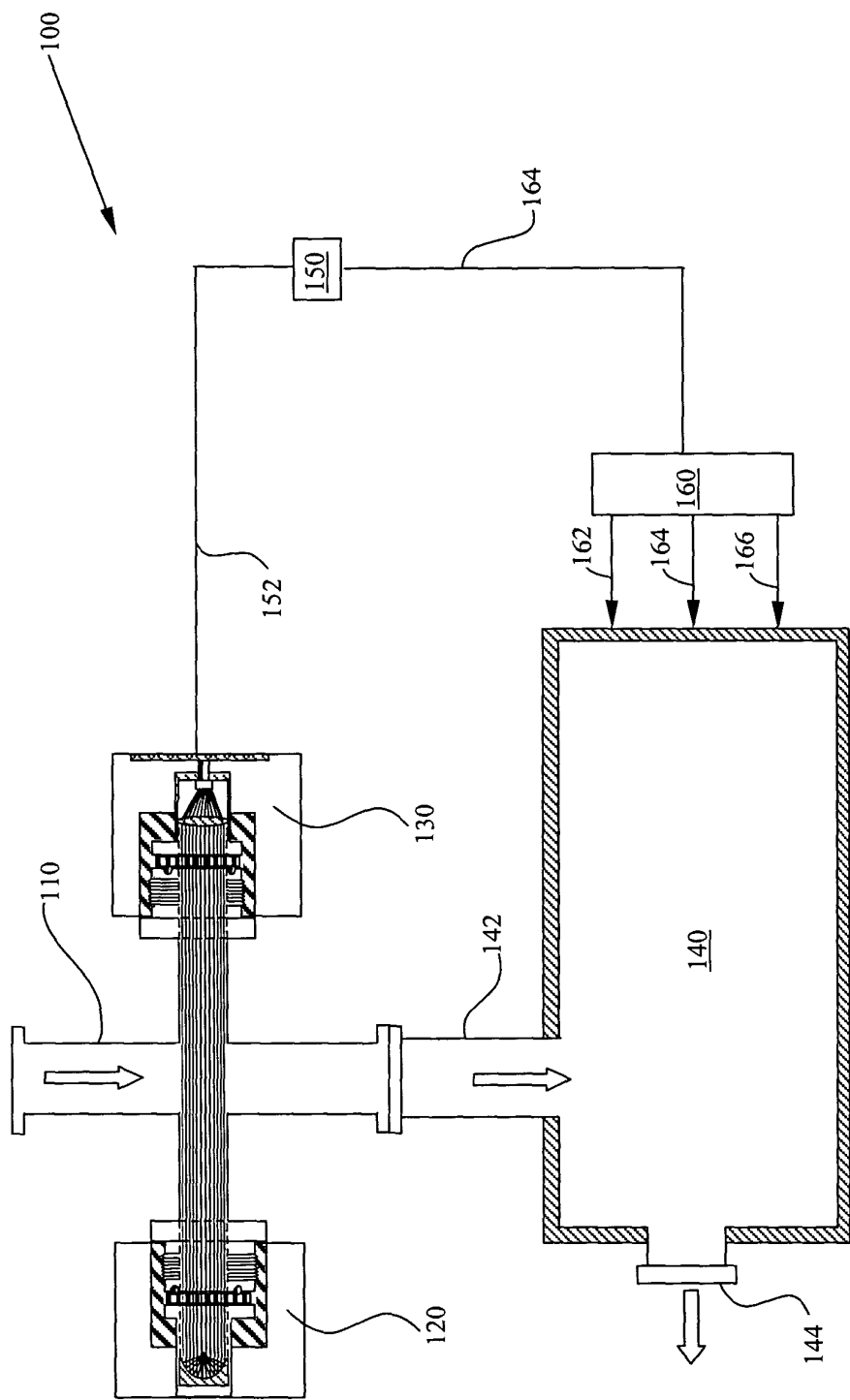


Figure 3

1000 Wafer TEOS PECVD Dep/Clean Marathon Process Effluent
Sensor

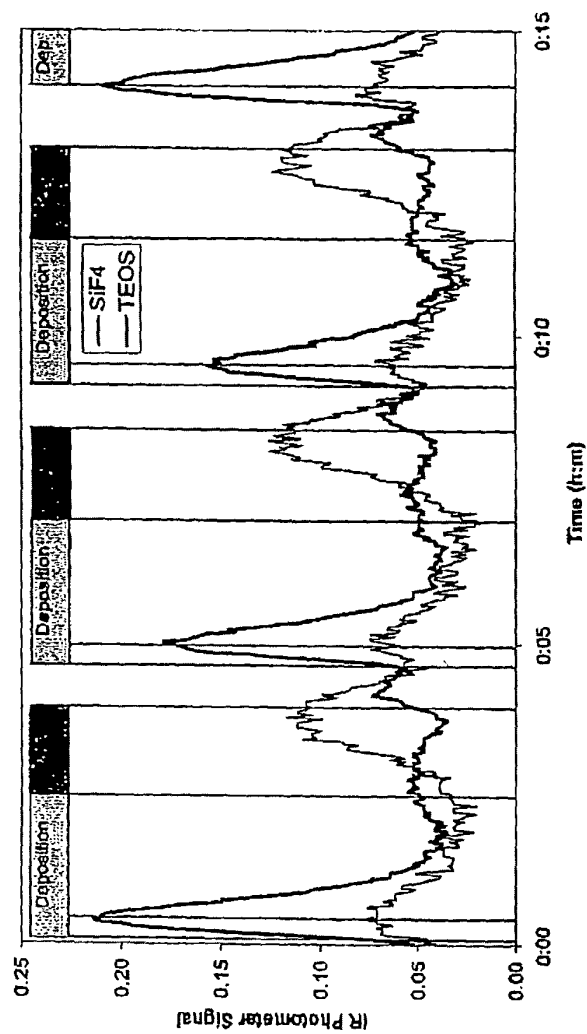


Figure 4

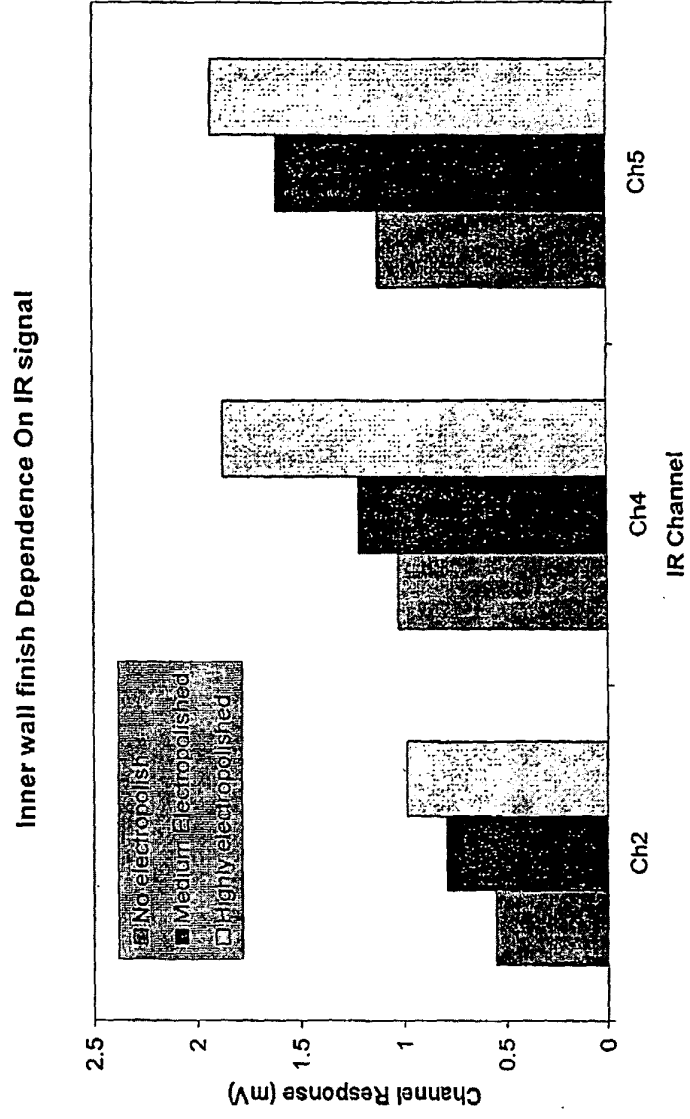


Figure 5

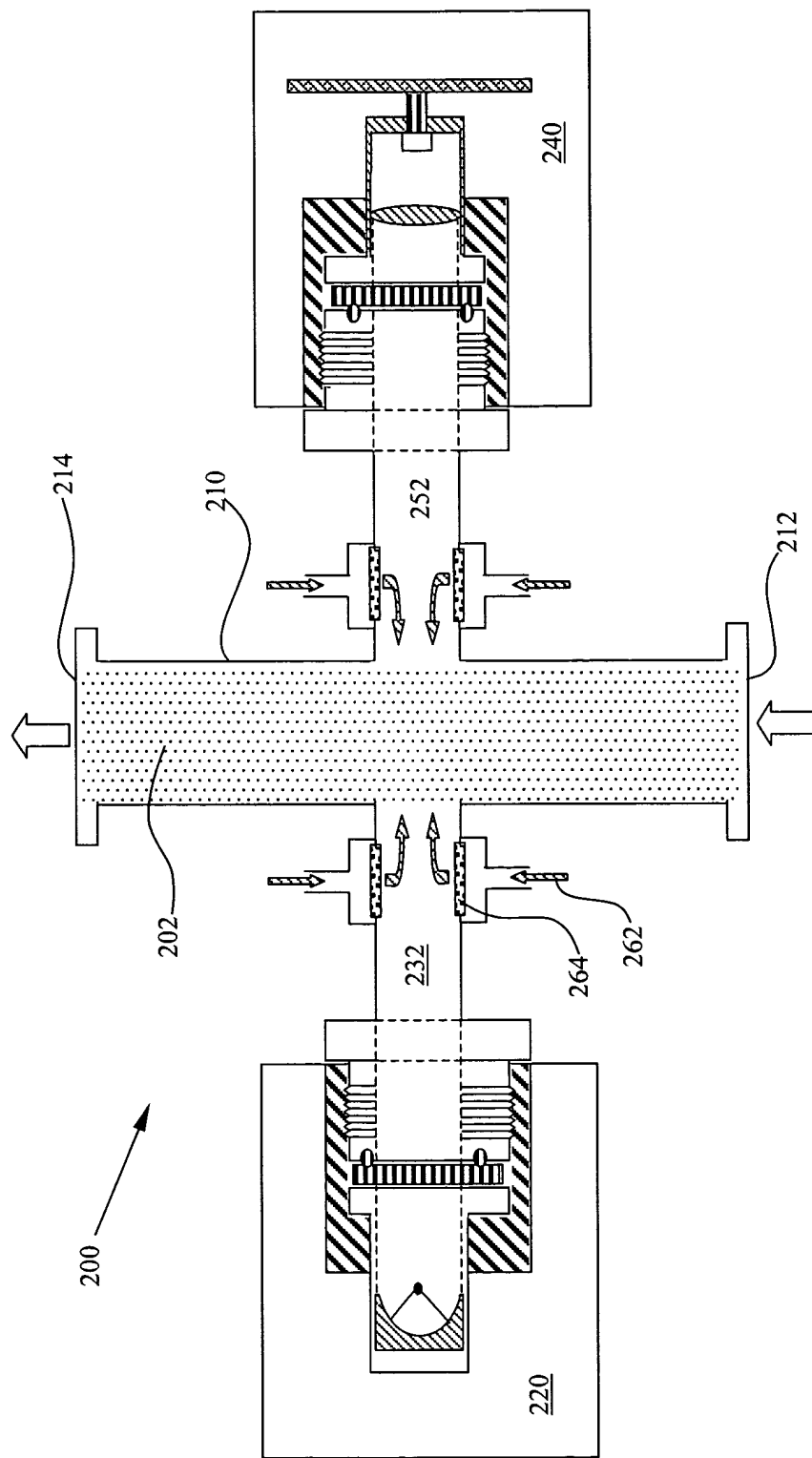


Figure 6

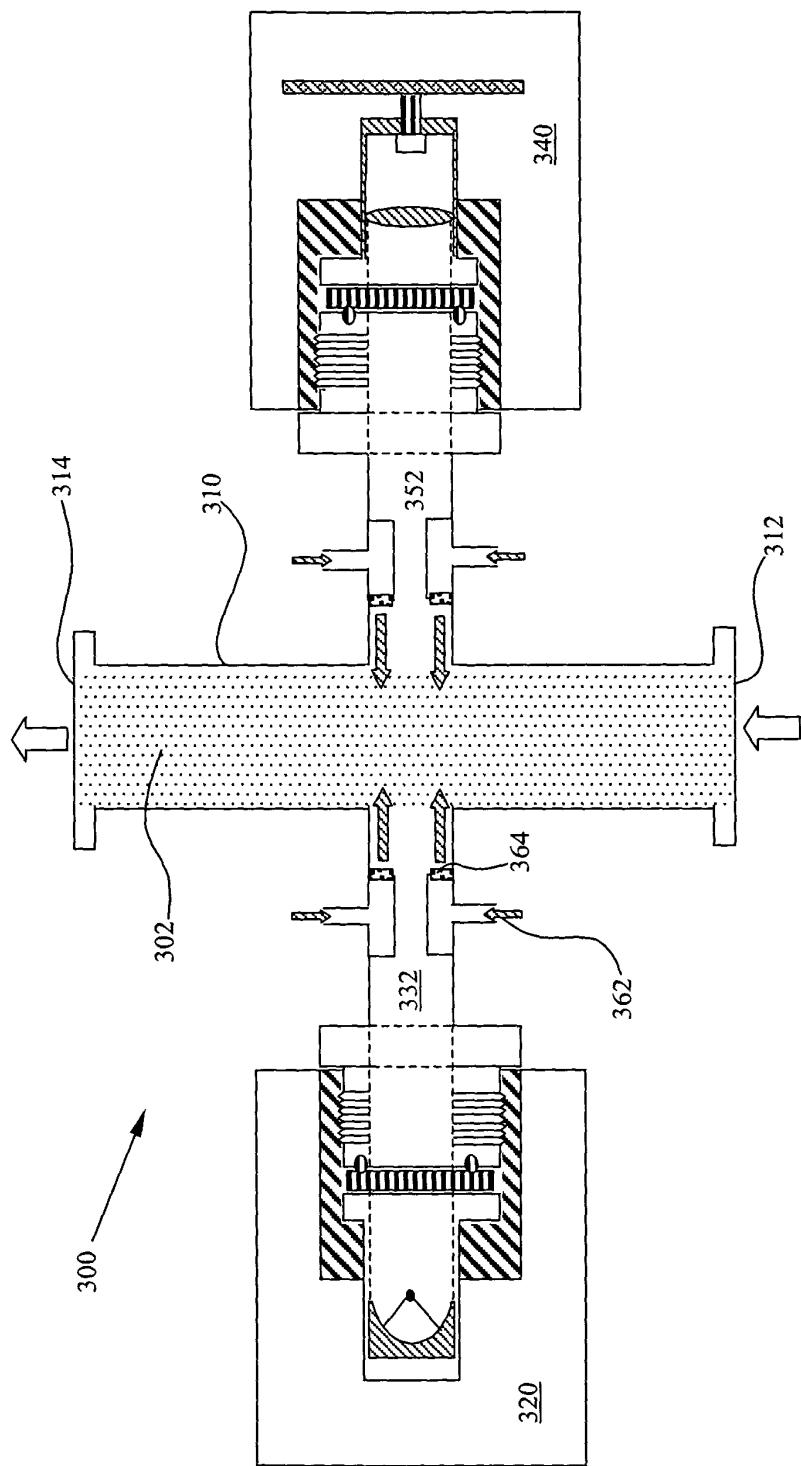


Figure 7

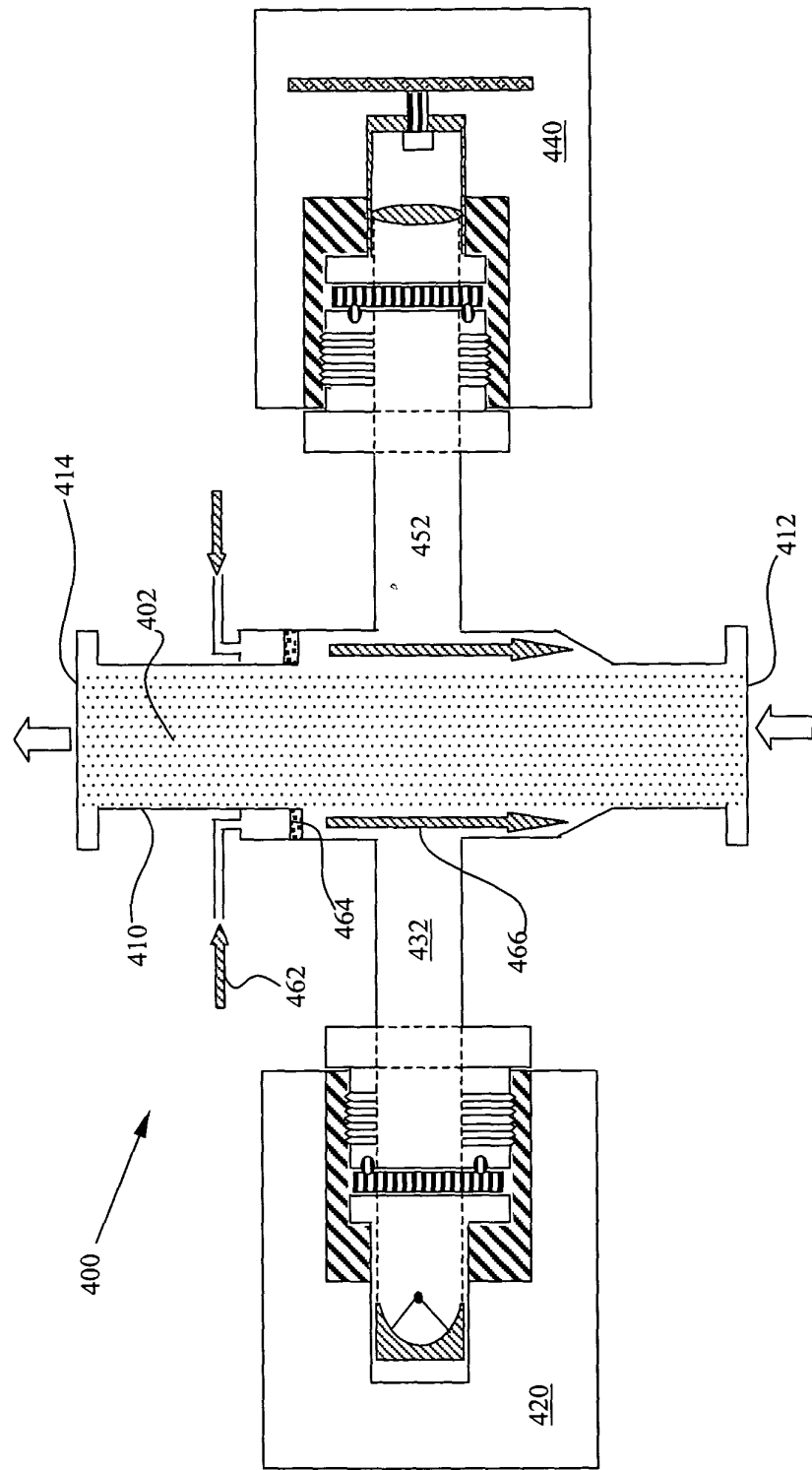


Figure 8